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566.38683CX1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: YOSHIDA, et al.

Serial No.: 10/042,271

Filed: January 11, 2002

For: ABRASIVE METHOD OF POLISHING TARGET MEMBER AND
PROCESS FOR PRODUCING SEMICONDUCTOR DEVICE

Group: 3723

Examiner: Not yet assigned

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**INFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. §1.97 AND §1.98**

TECHNOLOGY CENTER R3,

Mail Stop DD
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

September 3, 2003

Sir:

In the matter of the above-identified application, applicants are submitting herewith a copy of a communication from a foreign patent office in a counterpart foreign application and copies of the documents listed in the attached form equivalent to Form PTO-1449 for the Examiner's consideration.

This Information Disclosure Statement is being submitted before the mailing date of a first office action on the merits, and is accompanied the following certification specified in 37 C.F.R. §1.97(e).

On information and belief, I hereby certify that the Korean Reference No. 1966-13577 contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

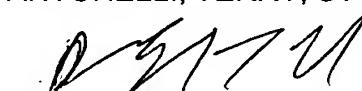
The attached U.S. Patent No. 5, 527,423 corresponds to the cited Korean Reference No. 1966-13577 and is provided in lieu of an English Translation thereof.

It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account No. 01-2135 (566.38683CX1) and please credit any excess fees to such Deposit Account.

Respectfully submitted,

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